

ADVANCED MATERIALS TECHNOLOGIES



POLYMER MICROELECTROMECHANICAL SYSTEMS

In article number 1800597, Yeowon Yoon, Inseok Chae, and co-workers combine dynamic mask lithography and a dry-state “plugging-out” sacrificial process to manufacture suspended polyethylene glycol diacrylate (PEG-DA) microstructures. Obtained PEG-DA cantilevers and membranes can sense humidity and pressure.